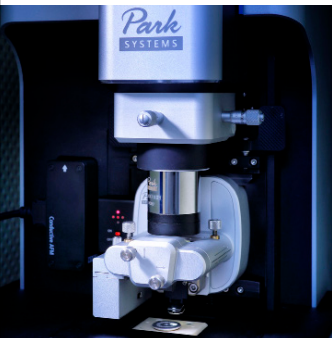




ATOMIC FORCE MICROSCOPY ANALYSIS SERVICE

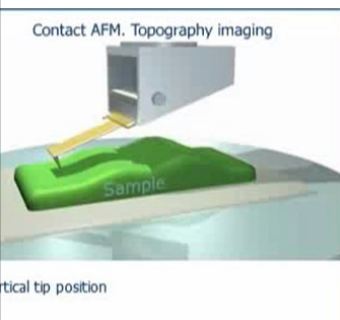
- SINGLE TRANSISTOR LOCALIZATION
- LOCAL I/V CURVE TRACING
- SURFACE ROUGHNESS MEASUREMENT
- TRUE NON-CONTACT AFM
- CONDUCTIVE AFM

ATOMIC FORCE MICROSCOPY ANALYSIS



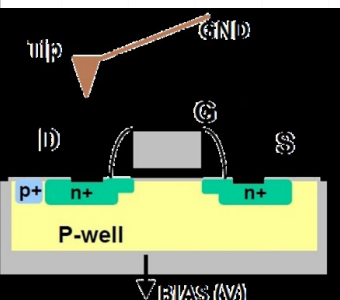
PARK NX10 FEATURES

- Expansion slot for advanced SPM modes and options
- High speed 24-bit digital electronics
- 100 μm x 100 μm XY scan area
- 15 m Z-direction scan range
- I/V curve measurement
- Maximum resolution of 0.05 nm



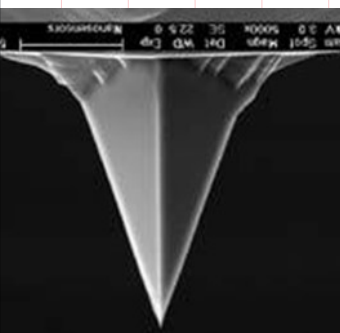
SCANNING MODES

- True Non-Contact AFM
- Basic Contact AFM
- Intermitted (Tapping) AFM



MEASUREMENT MODES

- Surface Morphology
- Conductive AFM (C-AFM)
- Electrostatic Force Microscopy (EFM)
- Force Modulation Microscopy (FMM)
- Lateral Force Microscopy (LFM)
- Magnetic Force Microscopy (MFM)
- Scanning Tunneling Microscopy (STM)



APPLICATION EXAMPLES

- Gate Oxide breakdown localization
- Open Via or Plug detection
- Molten Via or Plug detection
- Surface Roughness measurement
- Transistor I/V measurement